In re Appln. of TOTSUKA et al. Application No. Unassigned

ABSTRACT AMENDMENTS

Replace the Abstract with:

A method of manufacturing a semiconductor device using including a gallium nitride related semiconductor is provided. The method include a step of preparing a substrate whose having surface is formed by of a gallium nitride related semiconductor; a nitriding step of contacting the surface with atom-state atomic nitrogen, which is obtained by decomposing a nitrogen-containing gas by means of in a catalytic reaction, to thereby nitride the surface; and an electrode forming step of forming, on the surface, a gate electrode and source and drain electrodes opposing each other through across the gate electrode.